

JH/JA (entred
in part)

4-23-03

PATENT APPLICATION

00862.022476.



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshikazu MIYAJIMA et al.

Application No.: 10/022,506

Filed: December 20, 2001

For: EXPOSURE APPARATUS, DEVICE) April 14, 2003
MANUFACTURING METHOD, SEMICONDUCTOR : (Monday)
MANUFACTURING FACTORY, AND EXPOSURE)
APPARATUS MAINTENANCE METHOD :
:

The Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

Sir:

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4, 2003, and entitled "Amendments in a Revised Format Now Permitted."

In response to the Official Action dated January 13, 2003, please amend the above-identified application as follows:

4/16/2003 DEMMAHU1 00000113 1002566

01 51:1201
02 15:1202

840.00 OP
378.00 OP